

Electrostatic Probe Controller

Introduction

Our Electrostatic Probe Controller is for Langmuir probe diagnostics in fusion plasma. The Electrostatic Probe Controller can provide a bias excitation of up to ± 200 V and 4 A.

The Electrostatic Probe Controller is equipped with an Arbitrary Waveform Generator, which allows users to set the form, frequency, offset, and amplitude of the excitation signal as needed.

The Electrostatic Probe Controller can complete isolated detection of probe voltage and current signals.



Parameters

- Maximum Excitation Voltage: ± 200 V
- Maximum Excitation Current: 4 A
- Excitation Signal: Built-in Arbitrary Waveform Generator
- Signal Acquisition: Isolated current and voltage signal output (1500 VDC isolation)
- Communication Method: modbus
- Quantity: 2 sets of independent electrostatic probe controllers
- Form Factor: 1U rack-mounted chassis

Applications

The electrostatic probe can be applied in the fields of plasma research, space science research, geophysics, deep-space exploration, and vacuum coating technology.